



Searching for Eco-friendly molecules producing ·F and F · during the degradation in gaseous detectors by using quantum-chemical calculation

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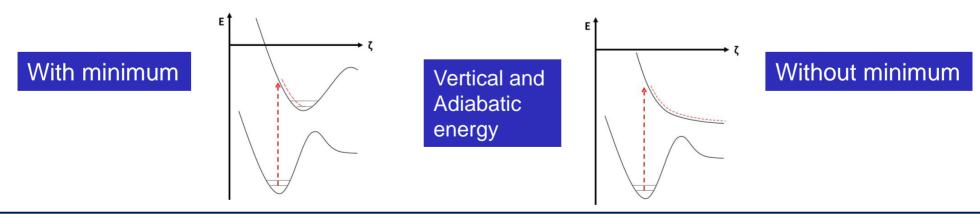


Molecule	Chemical formula	GWP (Global warming potential)	Hazards		
			Flammability	Health	Instability reactivity
freon	CF ₄	6630	0	1	0
HFC-1234ze	CF ₃ CHCHF	< 1			
HFC-1336mzz	CF ₃ -CH=CH-CF ₃				
HCFC-1233zd	CHCI=CH-CF ₃				
HFE-143m	CF ₃ -O-CH ₃				
HFE-245mc	CF ₃ -CF ₂ -O-CH ₃				



Examine and compare how three basic processes in plasma affect the stability of CF₄ and molecules from previous list

Examine ionization, excitation and electron attachment processes by calculations at Density-functional theory (DFT)(b3lyp and blyp) method with def2-tzvp basis set using Orca 5.0 quantum chemical package.



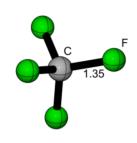
DRD1 – WG3- meeting, IGPC-Belgrade, June 18th 2024., CERN, Geneva, Switzerland

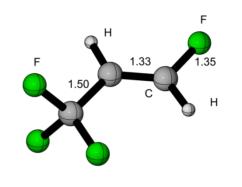




Ionization by losing electron

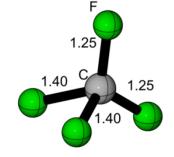
Ground state





Ground state

Ionized state



C 1.41 1.29
1.52 H

Ionized state

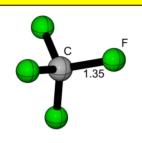
Vertical energy (eV) 14.46 Adiabatic energy (eV) 14.44 Vertical energy (eV) 10.80 Adiabatic energy (eV) 10.47

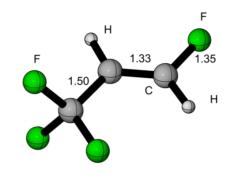




Electron excitation process

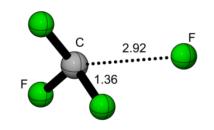
Ground state

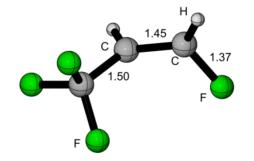




Ground state

Excited state





Excited state

Vertical energy (eV) 11.59 Adiabatic energy (eV) 5.37

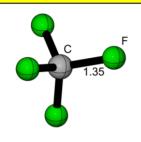
Vertical energy (eV) 4.44 Adiabatic energy (eV) 2.87

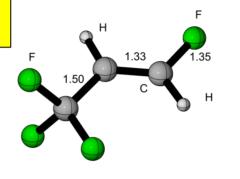




Ionization by attaching electron

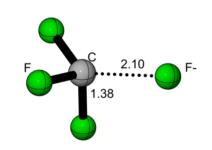
Ground state

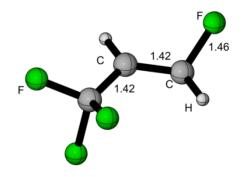




Ground state

electron attached -abstracted state





electron attached -abstracted state

Vertical energy (eV) 4.06 Adiabatic energy (eV) 1.12 Vertical energy (eV) 1.44 Adiabatic energy (eV) 0.44



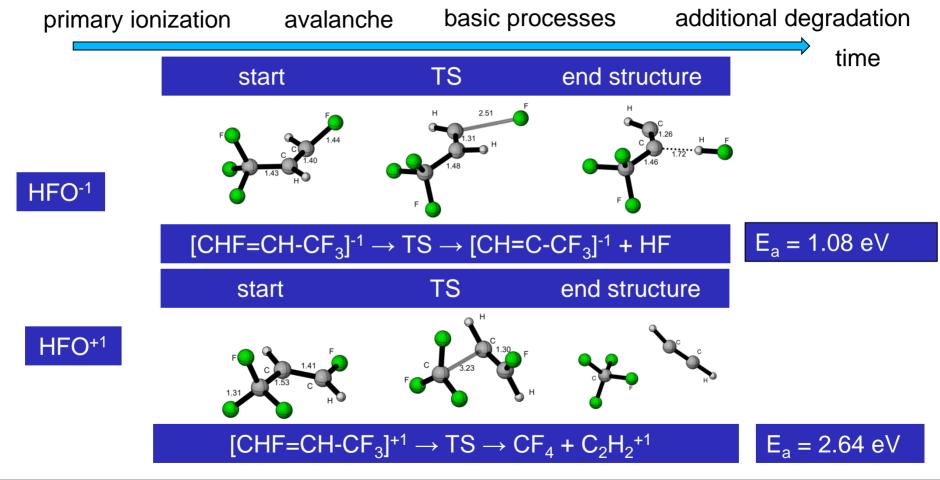


CF ₄	HFO
$CF_4 + e^- \rightarrow CF_4^+ + e^- + e^-$	HFO + $e^- \rightarrow HFO^{+1} + e^- + e^-$
$CF_4 + e^- \rightarrow CF_4^* + e^- \rightarrow \cdot CF_3 + \cdot F$	HFO + $e^- \rightarrow HFO^* + e^-$
$CF_4 + e^- \rightarrow \cdot CF_4^- \rightarrow \cdot CF_3 + F^-$	HFO + $e^- \rightarrow HFO^{-1}$

$$F^{-}$$
 + Anode $\rightarrow F + e^{-}$ + Anode
F + e^{-} $\rightarrow F^{-}$ spontaneous process











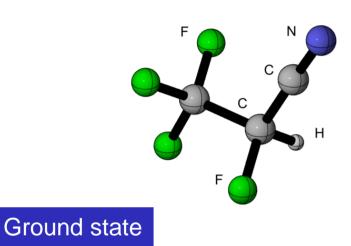
reaction	Activation energy E _a (eV)		
$\label{eq:cf4} \mbox{`CF_4$}^+ \rightarrow \mbox{ TS } \rightarrow \mbox{CF_3$}^+ + \mbox{ F^{\cdot}}$	0.05		
$\text{CF}_3{}^+ \rightarrow \text{TS} \rightarrow \ \ \cdot \text{CF}_2{}^+ \ + F \cdot$	6.26		
${}^{\textstyle \cdot}\text{CF}_2^{\; +} \to \text{TS} \to CF^+ \; + F^{\textstyle \cdot}$	2.84		
$\text{CF}^+ \ \rightarrow \text{TS} \rightarrow \cdot C^+ + F^.$	6.3		

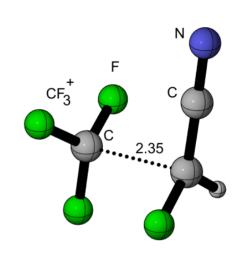
$$CF_3^+ \rightarrow CF_2^+ + F$$

 $CF_2^+ \rightarrow CF^+ + F$
 $CF^+ \rightarrow C^+ + F$







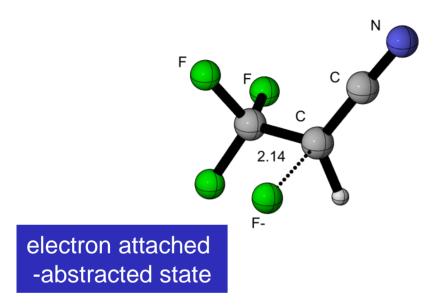


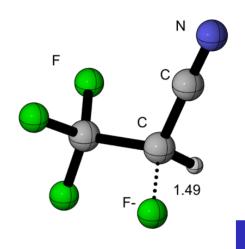
Ionized state

$$[CF_3-CHF-CN] + e^- \rightarrow CF_3^+ + [CHF-CN]^-$$









Excited state

$$[CF_3-CHF-CN] + e^- \rightarrow F^- + [CF3-CH-CN]$$

$$[CF_3\text{-}CHF\text{-}CN] + e^- \rightarrow e^- + F^- + [CF3\text{-}CH\text{-}CN]^+$$





$$F^- + Anode \rightarrow F + e^- + Anode$$

 $F + e^- \rightarrow F^-$ spontaneous process

Carbon tetrafluoride also has fast drift velocity and low diffusion, comparable to methane; CF₄-based gas mixtures for use in high-rate detectors have been studied extensively, Figure 4.27 (Christophorou *et al.*, 1979). Their main advantages for use in large volume detectors in particle physics are non-flammability and low sensitivity to neutrons; also, they do not form polymers in the avalanches, and even have etching properties capable of removing existing deposits on electrodes, as discussed in Chapter 16.

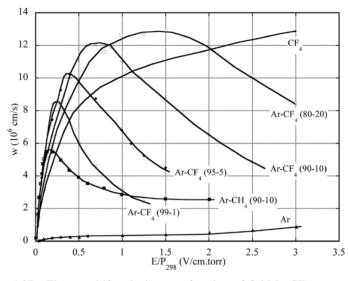


Figure 4.27 Electron drift velocity as a function of field in CF_4 , pure and in mixtures with argon (Christophorou *et al.*, 1979). By kind permission of Elsevier.









Processes on phase boundary